



Appl. No. 09/937,538  
Amdt. Dated March 5, 2004  
Reply to Office Action of December 8, 2003

Attorney Docket No. 81839.0102  
Customer No.: 26021

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Technology Center 2100

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Michihiro MIZUNO

Serial No: 09/937,538

Confirmation No.: 2057

Filed: September 25, 2001

For: METHOD FOR EVALUATING  
CONCENTRATION OF METALLIC  
IMPURITIES IN SILICON WAFER

Art Unit: 1743

Examiner: Siefke, Samuel P.

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Mail Stop Non-Fee Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 5, 2004

Date of Deposit

John P. Scherlach, Reg. No. 23,009

Name

*John P. Scherlach* 03/05/04

Signature

Date

**AMENDMENT**

Mail Stop Non-Fee Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action of December 8, 2003, please amend the  
above-referenced application as follows:

**Amendments** to the Claims are reflected in the Listing of Claims, which  
begins on page 2 of this paper.

**Remarks/Arguments** begin on page 6 of this paper.